

# Zuhal Tasdemir

## List of Publications by Year in descending order

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Version: 2024-02-01

16  
papers

166  
citations

1307594

7  
h-index

1372567

10  
g-index

16  
all docs

16  
docs citations

16  
times ranked

204  
citing authors

#	ARTICLE	IF	CITATIONS
1	Integrated humidity sensor based on SU-8 polymer microdisk microresonator. Sensors and Actuators B: Chemical, 2017, 242, 1115-1120.	7.8	62
2	A deep etching mechanism for trench-bridging silicon nanowires. Nanotechnology, 2016, 27, 095303.	2.6	20
3	Determination of the Elastic Behavior of Silicon Nanowires within a Scanning Electron Microscope. Journal of Nanomaterials, 2016, 2016, 1-6.	2.7	11
4	Top-down technique for scaling to nano in silicon MEMS. Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics, 2017, 35, 022001.	1.2	10
5	Monolithic Fabrication of Silicon Nanowires Bridging Thick Silicon Structures. IEEE Nanotechnology Magazine, 2018, 17, 1299-1302.	2.0	10
6	Real- and $Q$ -space travelling: multi-dimensional distribution maps of crystal-lattice strain ( $E_{044}$ ) and tilt of suspended monolithic silicon nanowire structures. Journal of Applied Crystallography, 2020, 53, 58-68.	4.5	10
7	State-of-the-art EUV materials and processes for the 7nm node and beyond. Proceedings of SPIE, 2017, , .	0.8	9
8	A new characterization approach to study the mechanical behavior of silicon nanowires. MRS Advances, 2021, 6, 500-505.	0.9	8
9	Monolithic Fabrication of Silicon Nanowires Bridging Thick Silicon Structures. IEEE Nanotechnology Express, 2015, 1, 2-5.	0.7	6
10	Studying resist performance for contact holes printing using EUV interference lithography. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2019, 18, 1.	0.9	6
11	Progress in EUV resists towards high-NA EUV lithography. , 2019, , .		6
12	Evaluation of EUV resists for 5nm technology node and beyond. , 2018, , .		4
13	Chemically-amplified EUV resists approaching 11 nm half-pitch. , 2018, , .		3
14	Contrast matching of line gratings obtained with NXE3XXX and EUV- interference lithography. , 2017, , .		1
15	Flexible Ceramic-Polymer Composite Substrates with Spatially Variable Dielectrics for Miniaturized RF Applications. Materials Research Society Symposia Proceedings, 2009, 1161, 5031.	0.1	0
16	Studying resist performance for contact holes printing using EUV interference lithography. , 2018, , .		0